

Fall 2008

EE 612: Nanoscale Transistors

### SOLUTION TO HW2: MOS Electrostatics (classical)

The purpose of this exercise is to review MOS electrostatics using the numerical simulation program, MOSCap. Before you begin this assignment, familiarize yourself with using MOSCap on [www.nanoHUB.org](http://www.nanoHUB.org). After logging on, find and select MOSCap. After you have familiarized yourself with running MOSCap, you are ready to proceed with the homework assignment.

For these exercises, assume:

$$N_A = 2.7 \times 10^{18} \text{ cm}^{-3} \text{ for the bulk doping}$$

$$EOT = 1.1 \text{ nm}$$

$$Q_F = 0.0$$

$$T = 300\text{K}$$

$$V_{DD} = 1.0\text{V}$$

Assume an  $n^+$  polysilicon gate with  $(E_F - E_C) = 0.0$  and ignore poly depletion.

- 1) Determine the following quantities by **analytical calculations** (assume  $V_g = 0.0\text{V}$ ). You may use the delta-depletion approximation for these calculations.
  - (i) The flatband voltage,  $V_{FB}$
  - (ii) The surface potential,  $\psi_s$
  - (iii) The electric field in the oxide,  $E_{ox}$
  - (iv) The electric field in the silicon at the surface,  $E_s$
  - (v) The depletion region depth,  $W_D$
  - (vi) The charge in the silicon,  $Q_s$
  - (vii) The charge on the gate,  $Q_G$
  - (viii) The voltage drop across the oxide,  $V_{ox}$
  - (ix) The threshold voltage for this MOS capacitor,  $V_T$

#### **Solution:**

- (i) The flatband voltage,  $V_{FB}$

$$V_{FB} = \phi_{ms} = -1.06\text{V}$$

- (ii) The surface potential,  $\psi_s$

$$\text{From } V_G = V_{FB} + \psi_s - \frac{Q_s}{C_{ox}} = 0, \quad Q_s \approx Q_D = -\sqrt{2q\epsilon_{si}N_A\psi_s} \text{ and answer of (i),}$$

$$\psi_s = 0.80V$$

(iii) The electric field in the oxide,  $E_{ox}$

$$\text{From } V_{ox} = -\frac{Q_s}{C_{ox}} = \varepsilon_{ox} E_{ox}, \quad E_{ox} = 2.4 \times 10^6 V/cm$$

(iv) The electric field in the silicon at the surface,  $E_s$

$$\text{From } \varepsilon_{ox} E_{ox} = \varepsilon_{si} E_{si}, \quad E_{si} = 0.8 \times 10^6 V/cm$$

(v) The depletion region depth,  $W_D$

$$Q_s \approx Q_D = -\sqrt{2q\varepsilon_{si}N_A\psi_s} = -8.34 \times 10^{-7} col/cm^2 = -qN_AW_D$$

$$W_D = 19.4nm$$

(vi) The charge in the silicon,  $Q_s$

$$Q_s \approx Q_D = -\sqrt{2q\varepsilon_{si}N_A\psi_s} = -8.34 \times 10^{-7} col/cm^2$$

(vii) The charge on the gate,  $Q_G$

$$Q_G = -Q_s$$

(viii) The voltage drop across the oxide,  $V_{ox}$

$$\text{From (i) and (ii), } V_{ox} = 0.26V$$

(ix) The threshold voltage for this MOS capacitor,  $V_T$

$$V_T = V_{FB} + 2\psi_B - \frac{Q_s(2\psi_B)}{C_{ox}} = 0.23V$$

- 2) Simulate the above MOS capacitor using MOSCap on the nanoHUB. Use the same p-type doping and gate oxide thickness as in problem (1), and a voltage range of 2V to -4V. You can answer the following questions by reading the data from the MOSCap plots or by downloading the data as text. From the results, deduce the following quantities:

### MOSCap parameters:

Model: single gate

Gate insulator thickness: 1.1nm

Gate insulator nodes: 20

Gate insulator dielectric constant: 3.9

Semiconductor thickness: 30 nm

Semiconductor layer nodes: 100

Semiconductor doping type: p-type

Gate electrode: n+ poly silicon

Gate electrode workfunction: 0 eV

Semiconductor doping:  $2.7e18 cm^{-3}$

Fixed charge density in gate oxide:  $0 cm^{-3}$

Ambient temperature: 300 K

Initial Voltage: 2 V

Final Voltage: -4 V

Number of voltage steps: 100

Frequency for AC analysis: low

## MOSCap plots:

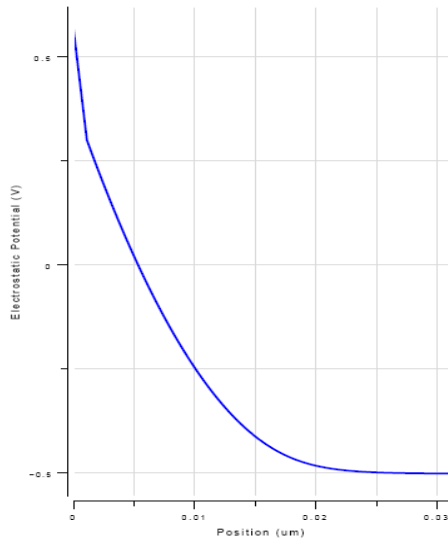


Fig. 1(a): Electrostatic potential at  $V_g = 0V$

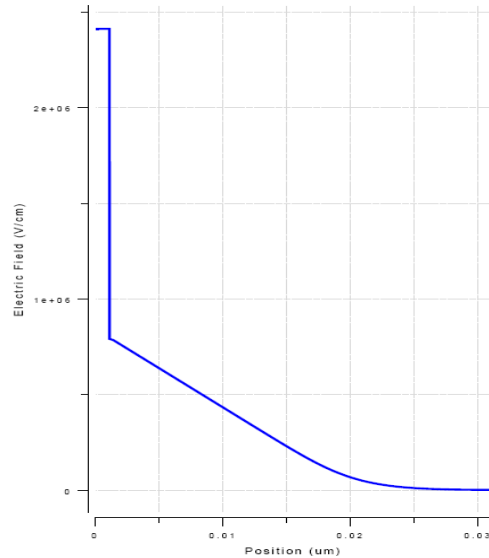


Fig 1(b): Electric field at  $V_g = 0V$

(i) The flatband voltage,  $V_{FB}$

**Solution:** Potential in the bulk:  $-0.502V$  (from Electrostatic Potential Plot)  
Potential at  $x=0$  (Gate-SiO<sub>2</sub> interface):  $0.566V$ .  
Flat band voltage:  $V_{FB} = -(0.566 - (-0.502)) = -1.068V$ .

(ii) The surface potential,  $\psi_s$  (as defined in the text by Taur and Ning)

**Solution:** Potential at  $x = 1.1nm$  (Si-SiO<sub>2</sub> interface):  $0.301V$  (Potential Plot)  
Surface potential:  $\psi_s = 0.301 - (-0.502) = 0.803V$

(iii) The electric field in the oxide,  $E_{OX}$

**Solution:** Electric field in the oxide:  $E_{OX} = 2.41e6$  V/cm (Electric field plot)

(iv) The electric field in the silicon at the surface,  $E_S$

**Solution:** Electric field at the silicon surface:  $E_S = 7.91e5$  V/cm (Electric field plot)

(v) The depletion region depth,  $W_D$

**Solution:** Net depletion charge in silicon:  $Q_D = -\epsilon_{si}E_S = -8.26e-7$  C/cm<sup>2</sup>

Depletion width:  $W_D = -Q_D/qN_A = 19.34 \text{ nm}$

(vi) The charge in the silicon,  $Q_S$

**Solution:** Net charge in silicon:  $Q_S = Q_D = -\epsilon_{si}E_S = -8.26e-7 \text{ C/cm}^2$

(vii) The charge on the gate,  $Q_M$

**Solution:** Net charge on the gate:  $Q_M = -Q_S = 8.26e-7 \text{ C/cm}^2$

(viii) The voltage drop across the oxide,  $V_{OX}$

**Solution:** Voltage drop across the oxide:  $V_{OX} = V(0 \text{ nm}) - V(1.1 \text{ nm}) = 0.27\text{V}$   
(Electrostatic Potential Plot)

(ix) The threshold voltage for this MOS capacitor,  $V_T$

**Solution:** From the lowest value of the C-V curve, the threshold voltage for this MOS capacitor is:  $V_T = 0.14\text{V}$ .

**Result comparison:**

	<u>Theory</u>	<u>MOSCap</u>
Flat band voltage	-1.06V	-1.07 V
Surface potential	0.80V	0.80 V
Electric field in the oxide	2.40e6 V/cm	2.41e6 V/cm
Electric field at the silicon surface	8.00e5 V/cm	7.91e5 V/cm
Depletion width	19.4 nm	19.3 nm
Net charge in silicon	-8.34e-6 C/cm <sup>2</sup>	-8.26e-7 C/cm <sup>2</sup>
Voltage drop across the oxide	0.26 V	0.27 V
Threshold voltage	0.23 V	0.14 V

3) From low frequency C-V characteristics of this MOS capacitor answer the following questions:

**MOSCap plot:**

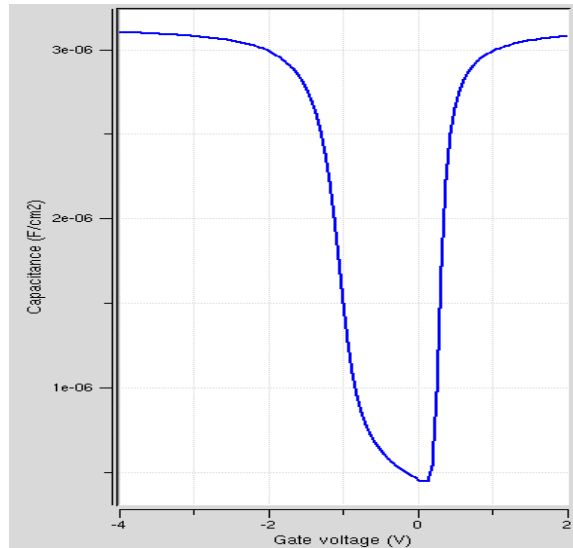


Fig. 2: C-V characteristic

- (i) Deduce the equivalent oxide thickness, electrical ( $EOT_{elec}$ ) at  $V_G = 1.0V$ .

**Solution:** At  $V_G = 1.0V$ ,  $C = 2.99e-6$  F/cm<sup>2</sup> (From the low frequency C-V plot.)  
 $EOT_{elec} = \epsilon_{ox}/C = 1.15$  nm.

- (ii) From the computed  $C-V$  plot, deduce the flatband voltage.

**Solution:** Theoretical prediction:  $C_{ox} = \epsilon_{ox}/t_{ox} = 3.14e-6$  F/cm<sup>2</sup>.  
 $L_D = (\epsilon_{si}k_B T / q^2 N_A)^{1/2} = 2.52$  nm.  $C_S(FB) = \epsilon_{si}/L_D = 4.15e-6$  F/cm<sup>2</sup>.  
 $C_{FB} = C_{ox}C_S(FB)/(C_{ox}+C_S(FB)) = 1.79e-6$  F/cm<sup>2</sup>.  
 From the MOSCap C-V plot,  
 At  $V_G = V_{FB} = -1.07$  V,  $C_{FB} = 1.80e-6$  F/cm<sup>2</sup>

- (iii) Deduce the semiconductor capacitance in accumulation and compare it to the expected value,  $Q_s / (2k_B T / q)$ .

**Solution:** At  $V_G = -4V$ ,  $C = 3.1e-6$  F/cm<sup>2</sup> (From the low frequency C-V plot.)  
 $C_S = C_{ox}C/(C_{ox} - C) = 24.335e-5$  F/cm<sup>2</sup>.  
 At  $V_G = -4V$ ,  $E_S = 2.07e6$  V/cm (From electric field at final bias.)  
 $Q_S = -\epsilon_{si}E_S = -2.15e-6$  C/cm<sup>2</sup>.  
 $C_S = Q_S / (2k_B T / q) = 4.17e-5$  F/cm<sup>2</sup> (Expected value.)

- 4) Estimate the effect of poly depletion on this capacitor by computing  $C_{MAX}/C_{OX}$  for  $N_P = 1e20$ ,  $1.5e20$ , and  $3e20 \text{ cm}^{-3}$ .

**Solution:** Using: 
$$\frac{C_{MAX}}{C_{OX}} = \frac{1}{1 + \sqrt{8k_B T \epsilon_{OX}^2 / \epsilon_{Si} q^2 t_{OX}^2 N_P}},$$

For  $N_P = 1e20 \text{ cm}^{-3}$ ,  $C_{MAX}/C_{OX} = 0.74$ .

For  $N_P = 1.5e20 \text{ cm}^{-3}$ ,  $C_{MAX}/C_{OX} = 0.78$ .

For  $N_P = 3e20 \text{ cm}^{-3}$ ,  $C_{MAX}/C_{OX} = 0.83$ .

Poly depletion effects are reduced ( $C_{MAX}/C_{OX}$  gets closer to unity) as  $N_P$  is increased.